


## TRANSMITTAL

Electronic Version v1.1

Stylesheet Version v1.1.0

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| <b>Title of<br/>Invention</b>  | HIGH-PRESSURE PROCESSING CHAMBER FOR A<br>SEMICONDUCTOR WAFER |   |
| Application Number :   | 10/680783   |  |
| Date :   | 2003-10-06  |   |
| First Named Applicant:   | Jones William Dale  |   |
| Confirmation Number:   | 5859  |   |
| Attorney Docket Number:  |   |   |
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| Submitted By:  |   | Elec. Sign.   |
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| Documents being submitted: | Files   |
|----------------------------|---|
| us-ids                     | SSI04001-usidst.xml<br>us-ids.dtd<br>us-ids.xsl |
| Comments                   |   |